

Substitute for form 1449/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(Use as many sheets as necessary)</i>			<i>Complete if Known</i> Application Number 09/715,935 Filing Date November 17, 2000 First Named Inventor BI et al. Art Unit 1762 Examiner Name Eric B. Fuller Attorney Docket Number 2950.16US02		
Sheet	1	of			
U.S. PATENT DOCUMENTS					
EXAMINER INITIAL*	Cite No. ¹	Document Number Number-Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	
EF		US-4,581,248	04/08/1986	Roche	
		US-4,681,640	07/21/1987	Stanley	
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		US-5,085,166	02/04/1992	Oka et al.	
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		US-5,246,745	09/21/1993	Baum et al.	
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		US-5,652,021	07/29/1997	Hunt et al.	
		US-5,858,465	01/12/1999	Hunt et al.	
	EF		US-6,013,318	01/11/2000	Hunt et al.
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FOREIGN PATENT DOCUMENTS					
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INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

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Application Number	09/715,935
Filing Date	November 17, 2000
First Named Inventor	BI et al.
Art Unit	1762
Examiner Name	Eric B. Fuller
Attorney Docket Number	2950.16US02

Sheet 2 of 3

NON PATENT LITERATURE DOCUMENTS

EXAMINER INITIAL ¹	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
EF		BESLING et al., Laser-Induced Chemical Vapor Deposition of Nanostructured Silicon Carbonitride Thin Films, 1997, pp. 544-553, Laboratory for Applied Inorganic Chemistry, Delft University of Technology, Julianalaan 136, 2628 BL Delft, The Netherlands.	
		BILENCCHI et al., CO ₂ Laser-Assisted Deposition of Boron and Phosphorus-Doped Hydrogenated Amorphous Silicon, American Institute of Physics 1985, pp. 279-281.	
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		BORNARD et al., LiNbO ₃ Thin Films Deposited on Si Substrates: a Morphological Development Study, Materials Chemistry and Physics, pp. 571-577, Elsevier Science B.V. 2002.	
		ICHINOSE et al., Deposition of LaMO ₃ (M=Co, Cr, Al) Films by Spray Pyrolysis in Inductively Coupled Plasma, Journal of Crystal Growth, pp. 59-64, Elsevier Science B.V. 1994.	
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		KIM et al., Deposition of MgO Thin Films by Modified Electrostatic Spray Pyrolysis Method, Thin Solid Films 376 (2000), pp. 110-114, Elsevier Science S.A. 2000.	
		MAGEE et al., Laser-Induced Conversion of Molecular Precursors to Thin Films and Deposited Layers, American Chemical Society 1990, pp. 232-235.	
		MARIC et al., Electrolyte Materials for Intermediate Temperature Fuel Cells Produced via Combustion Chemical Vapor Condensation, Electrochemical and Solid-State Letters, 6 (5) 2003, pp. A91-A95.	
		MEUNIER et al., Hydrogenated Amorphous Silicon Produced by Laser Induced Chemical Vapor Deposition of Silane, American Institute of Physics 1983, pp. 273-275.	
		MEUNIER et al., Laser-Induced Chemical Vapor Deposition of Hydrogenated Amorphous Silicon. I. Gas-Phase Process Model, American Institute of Physics 1987, pp. 2812-2821.	
EF		MEUNIER et al., Laser-Induced Chemical Vapor Deposition of Hydrogenated Silicon. II. Film Properties, American Institute of Physics 1987, pp. 2822-2829.	

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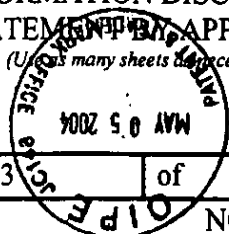
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EF		OLJACA et al., Deposition of Ba _x Sr _{1-x} TiO ₃ in Atmospheric Pressure Flame: Combustion Monitoring and Optimisation of Thin Film Properties, Surface Engineering, Vol. 19, No. 1, 2003, pp. 51-57.	
EF		VUKASINOVIC et al., Closed Loop Controlled Deposition of Ba _x Sr _{1-x} TiO ₃ Thin Films in Spray Flames, Surface Engineering, Vol. 19, No. 3, 2003, pp. 179-184.	

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